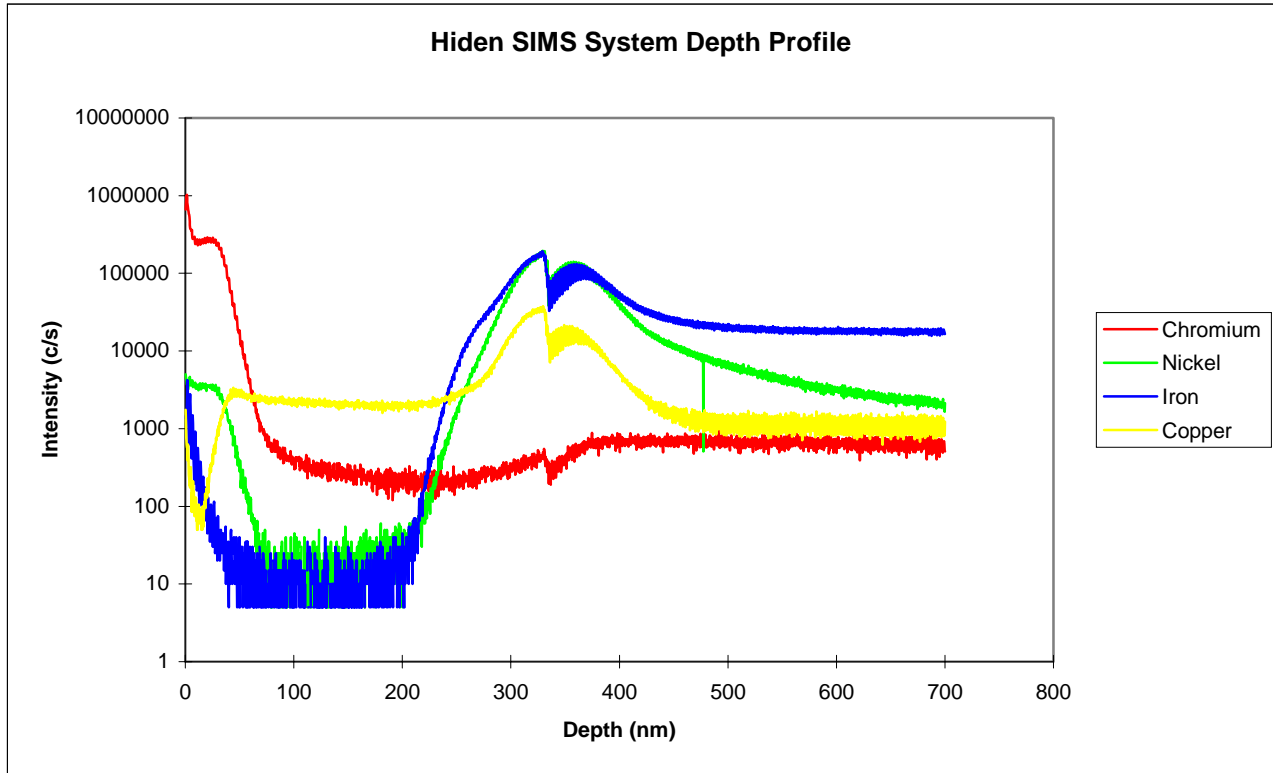


IG20 DATA



Depth profile on NiCr/Cu/NiFe/SiO<sub>2</sub> using a 5keV Argon primary beam with 650nA beam current  
The sputter rate is around 280nm per hour and a beam density of 215nA per sq mm



- **Beam densities up to 3 microA are achievable in raster mode**
- **Sputter rates up to approximately 1nm/sec are possible for some materials**